

Electronic Acknowledgement Receipt

EFS ID:	1324581
Application Number:	10606512
International Application Number:	
Confirmation Number:	5217
Title of Invention:	Method for cleaning a processing chamber and method for manufacturing a semiconductor device
First Named Inventor/Applicant Name:	Jung-Wook Kim
Customer Number:	22150
Filer:	Frank Chau/Mel Rodriguez
Filer Authorized By:	Frank Chau
Attorney Docket Number:	8054-23 (AW8037US/JJ)
Receipt Date:	20-NOV-2006
Filing Date:	26-JUN-2003
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Application Type:	Utility

Payment information:

Submitted with Payment	no
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File Listing:

Document Number	Document Description	File Name	File Size(Bytes)	Multi Part /.zip	Pages (if appl.)
1	Amendment - After Non-Final Rejection	8054-23-amd.pdf	859180	no	11

Warnings:

Information:**Total Files Size (in bytes):**

859180

This Acknowledgement Receipt evidences receipt on the noted date by the USPTO of the indicated documents, characterized by the applicant, and including page counts, where applicable. It serves as evidence of receipt similar to a Post Card, as described in MPEP 503.

New Applications Under 35 U.S.C. 111

If a new application is being filed and the application includes the necessary components for a filing date (see 37 CFR 1.53(b)-(d) and MPEP 506), a Filing Receipt (37 CFR 1.54) will be issued in due course and the date shown on this Acknowledgement Receipt will establish the filing date of the application.

National Stage of an International Application under 35 U.S.C. 371

If a timely submission to enter the national stage of an international application is compliant with the conditions of 35 U.S.C. 371 and other applicable requirements a Form PCT/DO/EO/903 indicating acceptance of the application as a national stage submission under 35 U.S.C. 371 will be issued in addition to the Filing Receipt, in due course.